

Appl. No.: 10/029,158  
Amdt. dated July 22, 2005  
Docket No.: A-69175-1/MSS (463035-650)  
Reply to Office Action of March 22, 2005



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

*In re* application of:

**Nam P. Suh et al.**

**Serial No.: 10/029,158**

**Filed: December 21, 2001**

**For: APPARATUS AND METHOD FOR  
CHEMICAL MECHANICAL  
POLISHING OF SUBSTRATES**

**Examiner: RACHUBA, Maurina T.**

**Art Unit: 3723**

**Confirmation No.: 5210**

**San Francisco, CA 94111**

**Date: July 22, 2005**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT/RESPONSE**

Sir:

In response to the final Office Action mailed March 22, 2005, Applicants submit the following amendments and remarks. A petition for a one-month extension of time with the requisite deposit account fee authorization is enclosed herewith, bringing the period of response to July 22, 2005.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 8 of this paper.